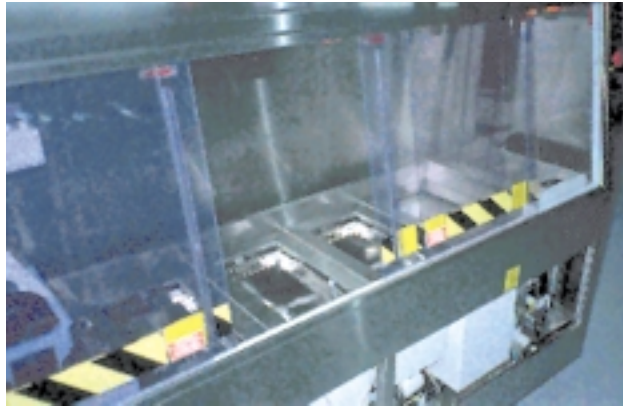


WET PROCESS STATIONS

Leatherwood Plastics' Wet Process Stations are designed to meet the needs of today's wafer process procedures. Each unit is engineered and fabricated to customer requirements, and designed and built to reduce impurities and contamination. Convenient operator access to electrical and plumbing control, and drop-in tanks are standard features. Many standard cabinet profiles are available, and cabinets can be built from standard or fire-retardant stress-relieved white polypropylene, or stainless steel, with leveling pads or casters.

Process controls are either front mounted, or panel mounted in an overhead control enclosure. These controls can include:

- ◆ PLC controlled operator interface panels
- ◆ Resistivity monitors
- ◆ Nitrogen flowmeters
- ◆ D.I. flowmeters
- ◆ Timers
- ◆ Heaters and pumps
- ◆ Fire suppression systems
- ◆ Nitrogen purged control panels
- ◆ Electrical outlets
- ◆ Fluorescent lighting
- ◆ Loss of nitrogen purge alarm
- ◆ Emergency stop buttons



Operator protection features include splash shields of acrylic or PVC, or complete wire glass door assemblies.

Plumbing and exhaust options include:

- ◆ High purity recirculating PVDF water lines
- ◆ Standard PVC drains or highly acid-resistance drain lines
- ◆ Bulk fill capability
- ◆ Water and chemical filters
- ◆ Plenum/sump flush
- ◆ Acid pumping or chemical delivery stations
- ◆ Dilution drains
- ◆ Plenum flush
- ◆ Chemical and waste canisters and carboys
- ◆ Balanced exhaust, through rear vents or lip exhaust
- ◆ Exhaust dampers at vent slots or in plenum
- ◆ Pneumatic or electric operated damper control
- ◆ Loss of airflow/vent alarm
- ◆ HEPA filters/blower units

All worksurfaces are assembled to each station's requirements, depending upon manual, linear, or rotational transfer operation.

Some available features are:

- ◆ Perforated or solid surfaces
- ◆ Ambient temperature baths
- ◆ Constant temperature baths
- ◆ Cascade rinse tanks
- ◆ Quick dump rinse tanks
- ◆ Ultrasonic rinse tanks
- ◆ Rinser-Dryers
- ◆ Glove rinses
- ◆ Hot plates
- ◆ Liquid or air aspirators
- ◆ Teflon D.I. water sprayers
- ◆ Recirculating goosenecks
- ◆ Nitrogen spray guns
- ◆ Vacuum connections
- ◆ Eye wash sprayers
- ◆ Splash shields or totally enclosed
- ◆ Fluorescent lighting

This plating bench features Automated Process Controls with programmable recipe capability. Unique rack design allows selective plating on both sides of wafers.

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